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E-Mail	BCLEE@POSTECH.AC.KR			Homepage			
					054-279-5079		
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02	.	Coater, Developer, Exposure	#				
03	.	E-Beam Lithography	#				
04	.	Mask Aligner	#				
05	.	ICP Etcher	#				
06	.	Etching on pattern	depth	#			
07	.	PR asher	02Plasma	shing	#		
08	.		#				
09	.	Furnace		#			
10	.	RTP		#			
11	.	PVD		#			
12	.	PE-CVD SiO2	#				
13	.	LP-CVD Poly si	#				
14	.	ALD AL2O3	#				
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